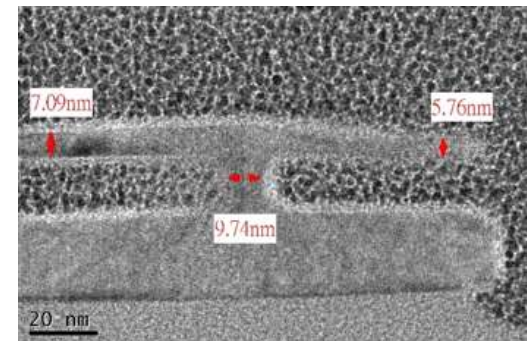
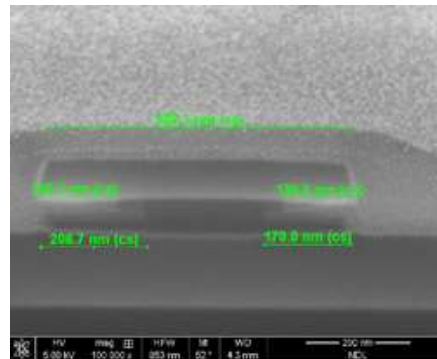
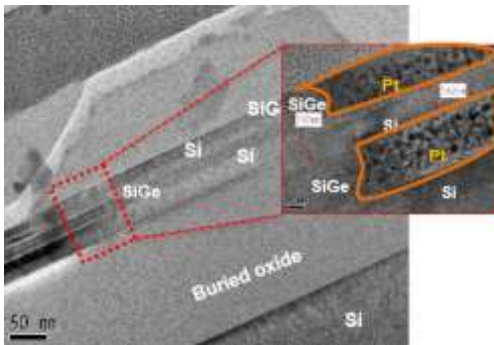


12 inch High Selectivity Etcher (AMAT Selectra Etcher)

Standard Process

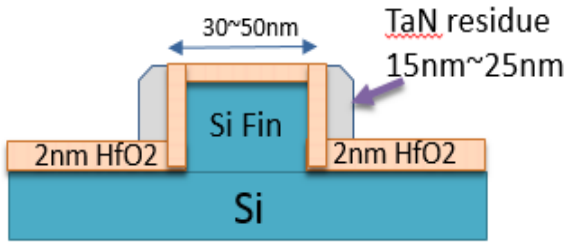
Front End Chamber Process

- SiGe Release :

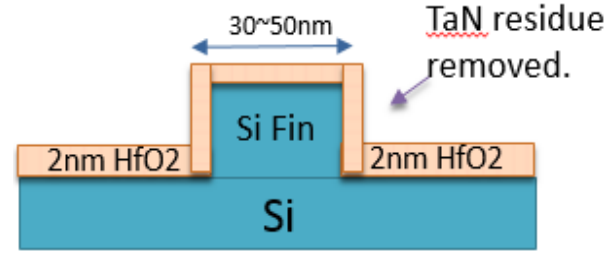


Back End Chamber Process

- Metal polymer remove : To remove metal polymer,



Width cross-section



Width cross-section

